Fabrication and Performance of Separately-Biasable Autiparallel-Pair "l' -Anode" Mixer Diodes Employing A CompactMultiple-Layer Integrated Bias Circuit at 210 GHz

T.-H. Lee, D. A. Humphrey, R. J. Dengler, 1. Mehdy S (Martin, A Pease, J. E. Oswald, R. P. Smith and P. H. Siegel

Jet Propulsion Laboratory California Institute of Technology Passidena CA 91109

ABSTRACT

A 210 GHz waveguide subharmonically-pumpedtaixer with integrated antiparallel-pair planar "Tanode" Schottky diodes and a novel compact multiple-layer bias circuit has been successfully fabricated and pigasured. The diode anodes are defined by electron-beam lithography using technology similar to that employed for T-gate transistors. A compact multiple-laverfilter structure provides individual biasing capability for each diode, which reduces the required local oscillator power for subharmonic mixing. Unbiased, a DS B mixer noise temperature of 1420 K was achieved with 6.4 mW of required LO power. Using separate mode bias to reduce the required LO power to 3.2 mW, the noise temperature increased slightly to 1640 K This is the lowest noise temperature reported for a schar, {(c), biased mixer at this frequency.

I. 1NTROI}UCTION

Not long after the. Sub-Harmonically-Punged (St 11) antiparallel-pair diode mixer arrangement was fust introduced by [1,2], an SHP receiver operating, at millimage. wave frequencies was demonstrated by the Ridio Astronomy group at Bell Laboratories [3,4]. These pioneers, together with groups that followed utilized whisker-contacted diode pairs to provide the antisymmetric 1-V characteristics that are essentialticallificat even harmonic mixing. Recent advances in fabrication technology have led the way to a new style of device that conventional vertical whiskers with horizontal air-bridged metal fingers and planari zedd tode structures. Thanks to the introduction of the surface channel etch technique [5], that made chip style lowparasitic planar diodes available, planar autiparatic) pair diodes were shown to perform as well as their whiskercontacted counterparts Up to 200 GHz [6], Motcover a recent subharmonic planar-diode mixer uti i jz i nganewo. gate-like technology to define the anodes, and a nivel substrate transfer technique to place active circuit elements on low-loss quartz, has yieldedextratow Parasitic devices and record noise performance at 200 GHz [7].

However, the excellent millimeter-wa~lc subharri10 iic-mixer performance nowbeingrealized by several groups

comes with a price; much higher required local oscillator power than needed for either fundamental or single-diode harmonic mixing. This is due to the difficulty involved in incorporating individual diode bias circuitry with the antiparallel-pair and is the most limiting factor in scaling S } IP mixers up to higher submillimeter-wave frequencies where significant local oscillator power is unavailable.

Prior implementations for adding individual-diode bias to SHP mixers in waveguide-based [8] or MMIC-based circuitry[9] have required fairly large bypass capacitors for DC isolating the two devices. This makes the implementation especially difficult in high-frequency waveguide structures where large open areas are often difficult to implement without engendering mode problems. A very compact bias circuit arrangement was recently demonstrated in an open structure quasi-optical SHP mixersystemat 180 (i) Iz [10], This arrangement utilizes a gap-cap configuration on one side of the two diodes and requires that there be a split in the feed lines going to the devices on this sick of the circuit Such an arrangement is not practical in a waveguide SHP circuit where there is generally not enough space to implement the feed-line gap.

In this paperwe describe a very compact multiple-layer bias circu it for an antiparallel-pair-diode arrangement which can be implemented in microstrip or stripline. In addition, we have coupled this bias circuit arrangement with our new T-anode diode process to produce extremely low-parasitic devices which yield very good mixer performance.

H.DEVICE/BLAS CLRCULT IMPLRMENTATION

The individual-diode bias concept we have realized was first proposed by the millimeter-wave development group at Rutherford Appleton I abs in the U.K. [1 1]. It ean be implemented in microstrip or stripline and uses a multiple-layer conductor/insulator arrangement to isolate the two diodes of the antiparallel pair. The configuration was first tested with optically formed diodes in an existing mixer block at 215 GHz [12].

The device geometry we have employed is an extension of IIEMT and FETT-gate technology and results in long thin anode, contacts which can be made with ultra-small areas. The advantages over more traditional oxide-patterned anodes lie

in no finger-to-anode alignment, reduced spreading resis tame, equivalent or reduced parasitic contact-ii aggregated tance and a more reproducible process. I Disadvantages in clude the need for e-beam direct write of the anodes and fingers and, perhaps, a slightly less robust device (due to), aving no oxide around the anode to help hold the metallic contact-finger in place).

The completed circuit structure looks very similar to that described in [6], and consists of a lithographically formed and rostrip RF filter circuit on each side of an antiparallel-pain GaAs diode, together on a fused quartz substrate) 1{ week in this instance, the two diodes are DC isolated on one side using a double-layered metallization pattern with mitted forming the insulating barrier. Strong capacitive coupling along the whole length of the two filter layers preserves the AC performance by providing a short circuit at the signal, (c) and IF frequencies. At the end of the filter, the two metallic layers split into individual bond pads for bringing in the separate device biasing. On the opposite side, the diodesare connected through a common ground to the mixerblock! The arrangement is shown in Figure 1.

The device anodes are nominally 0.25 wide by 4µmlong and are formed using our "T"-anode" process [7]. The '1-anode process, initially developed for high frequency resolution tunneling diodes [13], uses a trilayer PMMA coating exposed with multiple e-beam scans at different doses. I ach of the three PMMA layers has a different composition and molecular weight and, when spun and cured layer by laver, shows no evidence of intermixing. The mushroot o shape (or T-shape) of the anode is formed by selectively developing each PMMA layer in three developers. Air-bridged fragers that taper out from the anodes and connect to obtain pads are formed at the same time as the anodes. The lithographysis followed by the corporation of 6000 Å of time ium/platinum/gold to form the Schottky contact

The stacked filters that provide a separate biasing path for each active device are formed from a metal/nitride/nictal 111 i layer. The metal layers are titanium/golddeposited toy clex tron-beam evaporation and have a total thickness of 9000 Å The intermediate nitride layer is deposited by a plasmach hanced chemical vapor deposition system at 250 C to a thickness of 5000 Å. The nitride layer has to have low pin-hole density and good step coverage. The thickness of mitride determines the coupling capacitance required for proper firster performance. For our particular circuit, 6000 Å of nitlide results in approximately 1 ohm impedance at the lowest mixer IF frequency of 1.5 GHz. After the filter metallization, a surface channel etch [5] is performed which isolates the anode and cathode and forms the air-bridge contact fragers as seen in Figure 2. This is followed by a backside processthat transfers the devices and filter circuits from the GaAshost wafer to a low-loss quar tz substrate, I 'his process [14], deemed Quartz Upside-down Integrated Device (QUID), uses a thermally cured epoxy to bond the semiconductor wafer to the quartz cart ier. The GaAs substrate is then etched down to an AI GaAs etch stop layer. In the final processing step the remaining AlGaAs/GaAs is patterned and dry-etched, leaving only the areas that are needed for the ohmic and Schottky contacts

HUMEASUREMENTS

1 DC characteristics for the best separately-biasable device we have been able to fabricate to-date are given in Table 1. For comparison, the characteristics of our best unbiased T-anodepair diodes are also shown The diode areas are both about 1.2 µm². The slight asymmetry in the biasable-pair's turn-on knees is readily compensated with the external DC circuitry. The higher diode resistance, saturation current and ideality factor for the biasable pair means there is still room for significant device improvement.

Noise measurements on the device shown in Table 1, were performed at ≈200 GHz using the mixer block shown in Figure 1. The results are presented in Table 2, along with published data from other groups at a similar frequency. The lowest noise temperature obtained with this device was 1420 K DSB with a conversion loss of 7.6 dB and 6.4 mW of LO power with zero bias. When both diodes were biased at around S00 μA, the noise temperature increased slightly to 1640 K DSB with 8.4 dB conversion loss and 3.2 mW of LO power. The slight degradation in noise performance with the 3dB reduction in 1,() power is believed to be related to the large leakage current of this particular diode pair but more measurements art required before this can be confirmed.

IV. CONCLUSION

A novel separately-biasable-diode subharmonic mixer using 1"-anode technology and stacked filter structures has been fabricated and tested at: 200 GHz. Although the performance of the naixer is not as good as that of similar circuits with unbiased T-anode devices, it is better than any reported separately biased mixer at this frequency. Substantial reduction in required 1.0 power is obtained when separate bias is applied, although there is a slight penalty in overall noise performance. Substantial improvement in performance is to be expected with in provements in device DC characteristics.

ACKNOWLEDGMENT

The authors wish to thank M. Mazed and R, E. Muller for helpful discussions and advice. This work is supported by the Jet Propulsion Laboratory under contract with the National Aeronauties and Space. Administration.

REFERENCES

- [1] M.V. Schneider and W.W.Snell, Harmonically Pumped Stripline Down-Converter," *IEEE Trans. MTT.*, vol 23 no 5, pp. 271-275, Mar. 1975.
- [2] M. Cohn, J.E. Degenford, and B.A. Newman, "Harmonic Mixing with an Antiparallel Diode Pair," *IEEE Trans Met 1*. vol. 23, 110.8, pp. 667-673, Aug. 1975.
- [3] T.F. McMaster, M.V. Schneider, and W.W. Suc II Jr., "Millimeter Wave Receivers with Subharmonic Pump," 17 3-4-Trans. MTT., vol. 24, no. 12, pp. 948-952, Dec. 1 976.
- [4] E.R. Carlson and M.V. Schneider, "Subhatmonically Pumped Millimeter-Wave Receivers," *Digest of the 4th Int. Conf. Infrared&Millimeter Waves*, pp.82-83, Dec1979.
- [5] W. Bishop, K, McKinney, R.J. Mattauch, TCrowe and G. Green, "A Novel Whiskerless Diode for Millimeter and Submillimeter Wave Applications," *IEEE MITS Int. Microwave Sym. Digest, pp. 607-610*, June 1987.
- [6] P.H. Siegel, R.J. Dengler, I. Mehdi, J.F. Oswald, W. Bishop, T. Crowe, and R.J. Mattauch, "Measurements on a 215 GHz Subharmonically Pumped Waveguide Mixer Using Planar Back-to-Back Air-Bridge Schottky I Diodes," II Extrans. MIT., vol. 41, no.] 1, pp.1913-1921, Nov. 1993
- [7] I. Mehdi, S.C. Martin, RJ. Dengler, RP. Smith and E.H. Siegel, "Fabrication and Performance of Planar Schoolky Diodes with T-gate-like Anodes in 200 Gl b Subham onically-Pumped Waveguide Mixers," to be published on *IEEE Microwave and Guided Wave Letters*, Jan 1996
- [8] J.W. Archer, R.A. Batchelor and C.J. Smith, "Low-Para sitic, Planar Schottky Diodes for Millimeter Wave Integrated Circuits," *IEEE Trans. MTT.*, vol. 38, no. 1, pp. 1522, Jan 1990,

- [9] P.H Siegel, S, Weinreb, S. Duncan, W. Berk, A. Eskandatian, and 1).-M', Tu, "Design and Measurement of a 210 (;11~ Subharmonically Pumped GaAs MMIC Mixer-," *IEEE MIT-S Int. Mic. Sym. Digest*, pp. 603-606, 1992.
- [10] THI Ec, J.R East, C.Y. Chi, G.M. Rebeiz, and G.I. Haddad, "A Novel Biased Anti-Parallel Schottky Diode Structure for Subhatmonic Mixing," *IEEE Microwave and (bided Wave Letters*, vol 4, no. 10, pp.34–1-343, Oct. 1994.
- [11] B. Ellison, B. Maddison, and D. Matheson, private communication.
- [12] T.] ILec, I. Mchdi, R.J. 1 Dengler, A. Pease and P.H. Siegel, "A Tri-Layer Filter Structure for Individual Device Biasing of Subharmonically-Pumped Mixers Employing Antiparallel-Pair J Diodes," 1SDRS Conference, Charlottes-ville, VA. Dec. 7, 1995.
- [13] R.F. Muller, S.C. Martin, R.P. Smith, S.A. Allen, M. Reddy, i-1. Bhattachat ya, and M.J. W. Rodwell, "Electron Beam 1 ithography for the Fabrication of Air-Bridged, Submicron Schottky Collectors," *J. Vat. Sci. Technology B*, Vol 12, no. 6, pp. 3668-3672, 1994.
- [14] I. Mehdi, M Mazed, R 1 Dengler, A. Pease, M. Natzic, and P. I 1 Siegel, "Planat GaAs Schottky Diodes Integrated with Quartz Substrate Circuitry for Waveguide Subharmonic Mixers at 215 GHz," IEEE MIT-S ht. Microwave Sym. Digest, pp. 7'19-782., 1994.
- [15]P.H Siegel, 1 Mchdi, R Dengler, J. Oswald, A. Pease, T. Crowe, W. Bishop, R Mattauch, S. Weinreb, J. East and T. Lee, "Heterodyne Radiometer Development for the Earth Observing System Microwave Limb Sounder," *SPIE Conference on Infrared and Millimeter-Wave Engineering*, #1874,pp.124-137, Jan 1993.

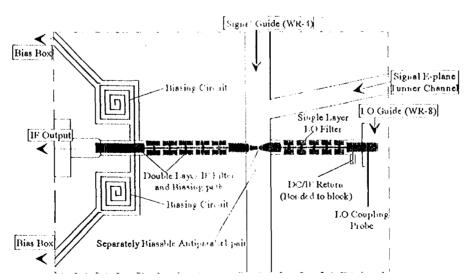
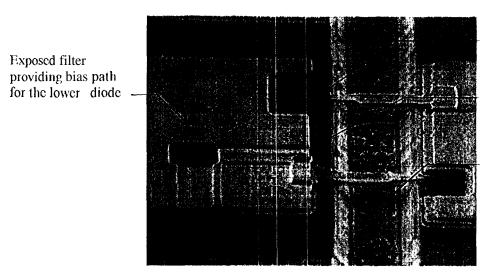


Figure 1. Center portion of the lower half of the mixer split-block that houses biasable diodes and microstrip circuits.



E:-beam defined 'l'-anode and air-bridge, passivated with PECVD nitride.

Buried filter providing bias path for the upper diode

Sur-face channel

Figure 2, SEM picture of the areas arounding the diode anodes showing multiple-layer bias scheme.

Parameters	$R_s(\Omega)$	94	$J_{s}(A)$	W(@) 10 μA.
Diode 1 ¹	13	13	3.5×10^{-13}	005586
Diode 2 ¹	16	13	5.7 x 10 ⁻¹³	005588
Best Diode made using	9.7	1 16	6.8 x 10 ⁻¹⁶	006692
same technology ²			sa ea .	

 $^{^{1}}$ Diode 1& 2 were fabricated on a 4 x 1017 cm 3 epilayerwith 12 tm 2 are aperanode.

l'able 1. Measured DC parameters of the anti-parallement de whose performance is presented in this paper and the best comparable unbiased descented with similar anode geometry.

Separately Biasable Subharmonic Mixer Configuration	——— Area per Anode (μm²)	Bias Condition	LOPower Required	DSB Noise Temperature (K)	Frequency
MMIC chip [15]	3.1	no bias	8.0 mW	2025 ""-	200 G} lz
		± 500 μ Δ	3 0 mW	2600	205 GHz
Quasi-optical	1.1	no bia	9 mW	1800	182 GHz
system [1 0]		± 400 µ A	4.5 mW	1850	
Waveguide	3.1	no bia-	16 mW	2380	195 GHz
microstrip ¹ [17]		± 800 µ A	$8\mathrm{mW}$	2730	
Waveguide	1,2	no bia-	6.4 mW	14?0	2.10 GHz
microstrip ²	#1;a-	Э. 500 µ А	3.7 mW	1640	

¹ Optically formed anodes with 2pm diameter

Table 2. Recently published data from segmentely biasable subharmonic mixers around 200 GHz.

This device was fabricated on a 2 x 1017 cm⁻³ cpilayerwith 1 µm² area peranode.

²This work,